Scalable growth of atomically-thin MoS₂ layers in conventional MOCVD system using molybdenum oxychloride as the molybdenum source

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To bring atomically-thin transition metal dichalcogenides (TMDs) to practical application, a highly reproducible process to grow them over a large scale is indispensable. Metalorganic chemical vapor deposition (MOCVD) typically fulfills the requirement, but the used metalorganic precursors in MOCVD of TMDs inevitably introduce carbon contamination, resulting in degraded film quality.

In this work, we develop a carbon-free highly reproducible route for the scalable growth of high-quality monolayer MoS₂ by pioneeringly selecting molybdenum oxychloride (MoO₂Cl₂) as the Mo source and uniquely integrating the precursor with a standard well-controlled MOCVD system. Specifically, combing with H₂S as the sulfur source and using catalytic Dragontrail glass (DT-glass) as the main substrate, we investigate the effect of MoO₂Cl₂ flux, temperature, and deposition time on the growth and confirm MoO₂Cl₂ with reasonably high vapor pressure could be well compatible with MOCVD system, enabling precise control of source for uniform nucleation and growth of MoS₂ over a large area. Benefiting from this, we successfully demonstrate the growth of carbon-free MoS₂ monolayers on DT-glass with decent crystalline, optical, and electrical properties. Additionally, our initial attempts have also confirmed the growth of ultrathin MoS₂ layers on other technologically-important substrates (e.g., SiO₂/Si and quartz) is possible using the proposed method, where MoS₂ exhibits superior optical quality and wafer-scale uniformity. This work provides a new avenue for the large-scale production of high-quality MoS₂ monolayers and facilitates their use in practical applications. More discussion will be given at the conference.

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